

PATENT ASSIGNMENT

Electronic Version v1.1

Stylesheet Version v1.1

SUBMISSION TYPE:

NEW ASSIGNMENT

NATURE OF CONVEYANCE:

ASSIGNMENT

CONVEYING PARTY DATA

Name	Execution Date
Archimedes Technology Group, Inc.	02/03/2005

RECEIVING PARTY DATA

Name:	Archimedes Operating, LLC
Street Address:	5660 Eastgate Drive
City:	San Diego
State/Country:	CALIFORNIA
Postal Code:	92121

PROPERTY NUMBERS Total: 53

Property Type	Number
Patent Number:	5939029
Patent Number:	6258216
Patent Number:	6203669
Patent Number:	6235250
Patent Number:	6204510
Patent Number:	6252224
Patent Number:	6096220
Patent Number:	6248240
Patent Number:	6217776
Patent Number:	6251282
Patent Number:	6235202
Patent Number:	6139681
Patent Number:	6294781
Patent Number:	6322706
Patent Number:	6214223

PATENT

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REEL: 015661 FRAME: 0131

OP \$2120.00 5939029

Patent Number:	6403954
Patent Number:	6521888
Patent Number:	6410880
Patent Number:	6386374
Patent Number:	6303007
Patent Number:	6287463
Patent Number:	6515281
Patent Number:	6396223
Patent Number:	6326627
Patent Number:	6304036
Patent Number:	6356025
Patent Number:	6521210
Application Number:	10330526
Patent Number:	6541764
Patent Number:	6398920
Patent Number:	6632304
Patent Number:	6624380
Patent Number:	6639222
Application Number:	10775511
Application Number:	10272481
Patent Number:	6723248
Patent Number:	6787044
Patent Number:	6576127
Patent Number:	6585891
Patent Number:	6733678
Patent Number:	6730231
Patent Number:	6719909
Application Number:	10713318
Patent Number:	6726884
Patent Number:	6797176
Application Number:	10453906
Patent Number:	6773558
Application Number:	10321301
Application Number:	10459270
Application Number:	10775271

Application Number:	10994778
Patent Number:	6251281
Patent Number:	6293406

**CORRESPONDENCE DATA**

Fax Number: (619)688-1322

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Correspondent Name: Neil K. Nydegger

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Address Line 4: San Diego, CALIFORNIA 92103

NAME OF SUBMITTER:	Neil K. Nydegger
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**Total Attachments: 7**

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## ASSIGNMENT

WHEREAS, Archimedes Technology Group, Inc., a Delaware corporation, having offices at 5660 Eastgate Drive, San Diego, California 92121 ("Assignor"), has certain rights and title to those patents and patent applications set forth on the attached Schedule A (all such technology referred to herein as the "Technology/Intellectual Property"); and

WHEREAS, Archimedes Operating, LLC, a Delaware Limited Liability Company, having offices at 5660 Eastgate Drive, San Diego, California 92121 ("Assignee"), is desirous of acquiring an interest in the Technology/Intellectual Property:

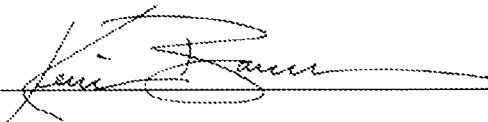
For good and valuable consideration, receipt of which is hereby acknowledged by Assignor, Assignor has assigned, and by these presents does assign to Assignee all of Assignor's right, title and interest in and to the Technology/Intellectual Property and to all foreign counterparts (including patent, utility model and industrial designs), and all future improvements thereon, and in and to any Letters Patent and Registrations which may hereafter be granted on the same in the United States and all countries throughout the world; and further including: (i) all income, royalties, and damages now and hereafter due and/or payable to Assignor, including without limitation, damages and payments for past or future infringements and misappropriations thereof; (ii) all rights to sue for past, present and future infringements or misappropriations thereof; and (iii) all rights corresponding to any of the above throughout the world. The right, title and interest is to be held and enjoyed by Assignee and Assignee's successors and assigns as fully and exclusively as it would have been held and enjoyed by Assignor had this assignment not been made, for the full term of any Letters Patent and Registrations which may be granted thereon, or of any division, renewal, continuation in whole or in part, substitution, conversion, reissue, prolongation or extension thereof.

Assignor further agrees that Assignor will, without charge to Assignee, but at Assignee's expense, (a) cooperate with Assignee in the prosecution of U.S. Patent applications and foreign counterparts on the Technology/Intellectual Property and any improvements, (b) execute, verify, acknowledge and deliver or cause to be delivered all such further papers, including patent applications and instruments of transfer and (c) perform such other acts as Assignee lawfully may request to obtain or maintain Letters Patent and Registrations for the Technology/Intellectual Property and improvements in any and all countries, and to vest title thereto in Assignee, or Assignee's successors and assigns.

IN TESTIMONY WHEREOF, Assignor has caused this Assignment to be duly executed by its duly authorized officer on the date set forth below.

DATED this 3rd day of February, 2005.

ARCHIMEDES TECHNOLOGY GROUP, INC.

By:   
Its: VICE PRESIDENT, FINANCE

STATE OF CALIFORNIA )  
                                  ) ss.  
COUNTY OF SAN DIEGO )

On February 3, 2005, before me, Debra D. Burns, Notary Public, personally appeared Kevin Bauer, ~~personally known to me~~ (or proved to me on the basis of satisfactory evidence) to be the person(s) whose name(s) is/are subscribed to the within instrument and acknowledged to me that he/she/they executed the same in his/her/their authorized capacity(ies), and that by his/her/their signature(s) on the instrument the person(s), or the entity upon behalf of which the person(s) acted, executed the instrument.

WITNESS my hand and official seal.

 (Seal)



Docket: 11252.100

Assignment from  
Archimedes Technology Group, Inc. to  
Archimedes Operating, LLC

<u>DOCKET</u>	<u>TITLE</u>	<u>COUNTRY</u>	<u>DATE FILED SERIAL NO.</u>	<u>DATE ISSUED PATENT NO</u>
11252.1	NUCLEAR WASTE SEPARATOR	USA	11/14/97 08/970,548	08/17/99 5,939,029
11252.1a	NUCLEAR WASTE SEPARATOR	Europe	03/19/99 99302138.5	09/01/04 1039479
11252.1b	NUCLEAR WASTE SEPARATOR	Japan	03/30/99 89822/99	02/01/02 3273928
11252.1c	NUCLEAR WASTE SEPARATOR	Canada	03/16/99 2,263,697	10/01/02 2,263,697
11252.1d	NUCLEAR WASTE SEPARATOR	Australia	03/17/99 21248/99	09/18/03 761554
11252.1.1	CHARGED PARTICLE SEPARATOR WITH DRIFT COMPENSATION (CIP)	USA	06/17/99 09/335,235	07/10/01 6,258,216
11252.1.2	NUCLEAR WASTE SEPARATOR (DIV)	USA	03/24/99 09/275,699	03/20/01 6,203,669
11252.1.3	NUCLEAR WASTE SEPARATOR (CON)	USA	09/29/99 09/409,311	05/22/01 6,235,250
11252.4	DEVICE AND METHOD FOR ION ACCELERATION	USA	12/18/98 09/215,976	03/20/01 6,204,510
11252.5	CLOSED MAGNETIC FIELD LINE SEPARATOR	USA	12/18/98 09/216,585	6/26/01 6,252,224
11252.7	PLASMA MASS FILTER	USA	11/16/98 09/192,945	08/01/00 6,096,220
11252.7a	PLASMA MASS FILTER	Europe	11/01/99 99308652.9	02/18/04 1001450
11252.7b	PLASMA MASS FILTER	Japan	11/15/99 324564/99	11/14/03 3492960
11252.7c	PLASMA MASS FILTER	Canada	11/03/99 2,288,412	
11252.7d	PLASMA MASS FILTER	Australia	11/16/99 59437/99	12/04/03 764430
11252.7.1	PLASMA MASS FILTER (CIP)	USA	12/15/99 09/464,518	06/19/01 6,248,240
11252.7.1a	PLASMA MASS FILTER	Europe	07/14/00 00306012.6	
11252.7.1b	PLASMA MASS FILTER	Japan	08/28/00 2000-256655	
11252.7.1c	PLASMA MASS FILTER	Canada	07/07/00 2,313,756	

<u>DOCKET</u>	<u>TITLE</u>	<u>COUNTRY</u>	<u>DATE FILED SERIAL NO.</u>	<u>DATE ISSUED PATENT NO</u>
11252.7.1d	PLASMA MASS FILTER	Australia	08/01/00 48957/00	06/24/04 770948
11252.7.2	CENTRIFUGAL FILTER FOR MULTI-SPECIES PLASMA (CIP)	USA	01/05/00 09/479,276	04/17/01 6,217,776
11252.7.3	PLASMA FILTER WITH HELICAL MAGNETIC FIELD (CIP)	USA	12/08/99 09/456,795	06/26/01 6,251,282
11252.7.3a	PLASMA FILTER WITH HELICAL MAGNETIC FIELD	Japan	10/16/00 2000-315338	10/22/04 3609711
11252.7.4	NEGATIVE ION FILTER (CIP)	USA	11/30/99 09/451,693	06/26/01 6,251,281
11252.7.4a	NEGATIVE ION FILTER	Japan	10/16/00 2000-315317	
11252.7.4b	NEGATIVE ION FILTER	Europe	09/15/00 00308037.1	
11252.7.5	TANDEM PLASMA MASS FILTER (CIP)	USA	08/08/00 09/634,925	05/22/01 6,235,202
11252.7.5a	TANDEM PLASMA MASS FILTER	Japan	05/01/01 2001-134412	08/06/04 3584007
11252.7.5b	TANDEM PLASMA MASS FILTER	Russia	08/07/01 2001122156	06/10/04 2229924
11252.7.5c	TANDEM PLASMA MASS FILTER	Europe	04/11/01 01201375.1	
11252.8	PLASMA ASSISTED PROCESS VESSEL CLEANER	USA	03/09/99 09/265,189	10/31/00 6,139,681
11252.10	ELECTROMAGNETIC MASS DISTILLER	USA	04/23/99 09/298,543	09/25/01 6,294,781
11252.12	RADIAL PLASMA MASS FILTER	USA	07/14/99 09/353,689	11/27/01 6,322,706
11252.13	TOROIDAL PLASMA MASS FILTER	USA	07/14/99 09/354,358	04/10/01 6,214,223
11252.16	LINEAR FILTER	USA	12/08/99 09/456,786	06/11/02 6,403,954
11252.16b	LINEAR FILTER	Europe	09/15/00 00308038.9	
11252.17	INVERTED ORBIT FILTER	USA	01/20/00 09/489,191	02/18/03 6,521,888
11252.17b	INVERTED ORBIT FILTER	Europe	09/15/00 00308070.2	
11252.18	INDUCTION PLASMA TORCH LIQUID WASTE INJECTOR	USA	01/10/00 09/480,097	06/25/02 6,410,880
11252.18a	INDUCTION PLASMA TORCH LIQUID WASTE INJECTOR	Japan	01/09/01 2001-000929	10/01/04 3603028
11252.18b	INDUCTION PLASMA TORCH LIQUID WASTE INJECTOR	Europe	12/01/00 00310685.3	
11252.21	MULTI-MASS FILTER	USA	08/21/00 09/643,204	09/25/01 6,293,406

<u>DOCKET</u>	<u>TITLE</u>	<u>COUNTRY</u>	<u>DATE FILED SERIAL NO.</u>	<u>DATE ISSUED PATENT NO</u>
11252.21a	MULTI-MASS FILTER	Europe	08/01/01 01202935.1	
11252.21b	MULTI-MASS FILTER	Japan	08/20/01 2001-249300	
11252.21.1	MULTI-MASS FILTER WITH ELECTRIC FIELD VARIATIONS (DIV)	USA	05/17/01 09/860,161	05/14/02 6,386,374
11252.22	PLASMA INJECTOR	USA	11/15/99 09/440,358	10/16/01 6,303,007
11252.22a	PLASMA INJECTOR	Japan	10/16/00 2000-314897	
11252.22b	PLASMA INJECTOR	Europe	09/15/00 00308040.5	
11252.23	COLLECTOR CUP	USA	11/15/99 09/440,547	09/11/01 6,287,463
11252.23a	COLLECTOR CUP	Japan	10/16/00 2000-314913	
11252.23b	COLLECTOR CUP	Europe	09/15/00 00308072.8	
11252.24	STOCHASTIC CYCLOTRON ION FILTER (SCIF)	USA	06/23/00 09/602,518	02/04/03 6,515,281
11252.24a	STOCHASTIC CYCLOTRON ION FILTER (SCIF)	Europe	06/12/01 01202237.2	
11252.24b	STOCHASTIC CYCLOTRON ION FILTER (SCIF)	Japan	06/22/01 2001-190153	12/10/04 3626118
11252.26	CUSP FILTER	USA	04/21/00 09/556,047	05/28/02 6,396,223
11252.28	MASS FILTERING SPUTTERED ION SOURCE	USA	08/02/00 09/630,847	12/04/01 6,326,627
11252.29	SYSTEM AND METHOD FOR INITIATING PLASMA PRODUCTION	USA	08/08/00 09/634,926	10/16/01 6,304,036
11252.30	SHIELDED RF ANTENNA	USA	10/03/00 09/678,646	03/12/02 6,356,025
11252.31	METHOD FOR IMAGING MALIGNANT TUMORS USING CARBON 13 WITH MRI	USA	10/13/00 09/736,526	02/18/03 6,521,210
11252.31b	METHOD FOR IMAGING MALIGNANT TUMORS USING CARBON 13 WITH MRI	Japan	12/13/01 2001-380166	
11252.31.1	A SYSTEM FOR IMAGING MALIGNANT TUMORS USING CARBON 13 (DIV)	USA	12/27/02 10/330,526	
11252.32	HELICALLY SYMMETRIC PLASMA MASS FILTER	USA	03/21/01 09/814,082	04/01/03 6,541,764
11252.33	PARTIALLY IONIZED PLASMA MASS FILTER	USA	02/21/01 09/790,357	06/04/02 6,398,920
11252.33a	PARTIALLY IONIZED PLASMA MASS FILTER	Europe	11/21/01 01204470.7	



<u>DOCKET</u>	<u>TITLE</u>	<u>COUNTRY</u>	<u>DATE FILED SERIAL NO.</u>	<u>DATE ISSUED PATENT NO</u>
11252.33b	PARTIALLY IONIZED PLASMA MASS FILTER	Japan	11/27/01 2001-360246	
11252.34	MOLTEN SALT COLLECTOR FOR PLASMA SEPARATIONS	USA	07/11/01 09/903,304	10/14/03 6,632,304
11252.34a	MOLTEN SALT COLLECTOR FOR PLASMA SEPARATIONS	Europe	07/10/02 02077791.8	
11252.34b	MOLTEN SALT COLLECTOR FOR PLASMA SEPARATIONS	Japan	07/11/02 2002-202475	
11252.35	DEVICE FOR RECOVERING SODIUM HYDRIDE	USA	07/10/01 09/903,321	09/23/03 6,624,380
11252.35b	DEVICE FOR RECOVERING SODIUM HYDRIDE	Japan	07/10/02 2002-236115	
11252.38	DEVICE AND METHOD FOR EXTRACTING A CONSTITUENT FROM A CHEMICAL MIXTURE	USA	11/15/01 09/999,053	10/28/03 6,639,222
11252.40	INJECTOR FOR PLASMA MASS FILTER	USA	02/10/04 10/775,511	
11252.40a	INJECTOR FOR PLASMA MASS FILTER	PCT	PCT App. to PTO 1-26-05	
11252.41	SYSTEM AND METHOD FOR RADIOACTIVE WASTE VITRIFICATION	USA	10/16/02 10/272,481	
11252.41a	SYSTEM AND METHOD FOR RADIOACTIVE WASTE VITRIFICATION	Europe	10/10/03 03078205.6	
11252.42	HIGH THROUGHPUT PLASMA MASS FILTER	USA	08/16/02 10/222,475	04/20/04 6,723,248 B2
11252.43	HIGH FREQUENCY WAVE HEATED PLASMA MASS FILTER	USA	03/10/03 10/385,073	09/07/04 6,787,044 B1
11252.43a	HIGH FREQUENCY WAVE HEATED PLASMA MASS FILTER	Europe	03/08/04 04075745.2	
11252.43b	HIGH FREQUENCY WAVE HEATED PLASMA MASS FILTER	Japan	03/09/04 2004-065454	
11252.44	PONDEROMOTIVE FORCE END PLUG FOR A PLASMA MASS FILTER	USA	02/28/02 10/086,575	06/10/03 6,576,127 B1
11252.45	PLAMSA MASS SEPARATOR USING PONDEROMOTIVE FORCES	USA	02/28/02 10/086,671	07/01/03 6,585,891
11252.47	LIQUID SUBSTRATE COLLECTOR	USA	02/28/02 10/086,950	05/11/04 6,733,678 B2
11252.47a	LIQUID SUBSTRATE COLLECTOR	Europe	02/14/03 03075437.8	
11252.47b	LIQUID SUBSTRATE COLLECTOR	Japan	12/24/02 2002-371916	
11252.48	PLASMA MASS FILTER WITH AXIALLY OPPOSED PLASMA INJECTORS	USA	04/02/02 10/115,216	05/04/04 6,730,231 B2
11252.50	BAND GAP PLASMA MASS FILTER	USA	04/02/02 10/114,900	04/13/04 6,719,909 B2
11252.50a	BAND GAP PLASMA MASS FILTER	Europe	03/12/03 03075734.8	
11252.50b	BAND GAP PLASMA MASS FILTER	Japan	12/24/02 2002-371840	

<u>DOCKET</u>	<u>TITLE</u>	<u>COUNTRY</u>	<u>DATE FILED SERIAL NO.</u>	<u>DATE ISSUED PATENT NO</u>
11252.51	HEAVY ION COLLECTOR FOR A PLASMA MASS FILTER	USA	11/14/03 10/713,318	
11252.53	ISOTOPE SEPARATOR	USA	06/12/02 10/171,480	04/27/04 6,726,884 B2
11252.54	PLASMA MASS FILTER WITH INDUCTIVE ROTATION DRIVE	USA	07/03/03 10/613,833	09/28/04 6,797,176 B1
11252.55	HIGH FREQUENCY ULTRASONIC NEBULIZER FOR HOT LIQUIDS	USA	06/03/03 10/453,906	
11252.55a	HIGH FREQUENCY ULTRASONIC NEBULIZER FOR HOT LIQUIDS	Europe	03/24/04 04075923.5	
11252.55b	HIGH FREQUENCY ULTRASONIC NEBULIZER FOR HOT LIQUIDS	Japan	03/29/04 2004-094288	
11252.56	FLUORINE GENERATOR	USA	10/15/02 10/272,513	8/10/04 6,773,558 B2
11252.56a	FLUORINE GENERATOR	Europe	10/10/03 03078203.1	
11252.56b	FLUORINE GENERATOR	Japan	10/14/03 2003-353233	
11252.57	BAND GAP MASS FILTER WITH INDUCED AZIMUTHAL ELECTRIC FIELD	USA	12/16/02 10/321,301	
11252.59	STRATIFIED DISCHARGE FOR DISSOCIATION OF ELECTRO- NEGATIVE MOLECULAR GAS	USA	06/11/03 10/459,270	
11252.60	MASS SEPARATOR WITH CONTROLLED INPUT	USA	02/10/04 10/775,271	
11252.61	SHIELDED ANTENNA	USA	11/22/04 10/994,778	